

JH Rhodes Polishing Pads



LP-57C

www.jhrhodes.com

PRIMARY POLISHING PAD - UNFILLED

The LP-57C is an unfilled, small pore size polyurethane pad. (modified version of LP-57) It is designed for silicon wafer primary polishing but has proven suitable for general polishing applications at moderate or higher pressures.

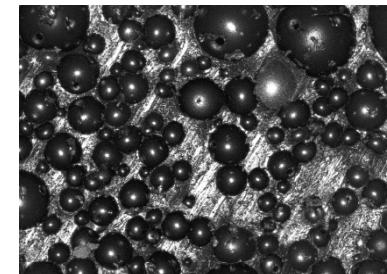
BENEFITS

- ✓Very stable performance, ✓Low edge roll-off
- ✓Long life, ✓Low noise and vibration

TYPICAL APPLICATIONS

Silicon

LP-57C PAD PROPERTIES (Average)				
FILLER	DENSITY [g/cm ³ (lb/ft ³)]	HARDNESS (Shore A)	COMPRESSIBILITY (%)	ELASTIC REBOUND (%)
None	0.53 (33.0)	88	8.0	92



Values are subject to change without notification.